

## CLAIM AMENDMENTS

1. (Currently Amended) A wafer boat for supporting silicon wafers, the wafer boat comprising:

a ceramic body having at least one wafer support structure sized to support a silicon wafer thereon;

C1 a ceramic coating disposed on a surface of the wafer support structure, the ceramic coating having an impurity migration preventing thickness that is substantially between 30 to 60 microns and a wafer contact surface, the wafer contact surface having a post coating surface finish;

wherein the post coating surface finish of the wafer contact surface substantially prevents frictional slip in the silicon wafers and is less than or substantially equal to [1] 0.4 micron]; and

wherein the wafer contact surface is less than or substantially equal to 1/2 of the surface area of the wafer].

2. (Original) The wafer boat of Claim 1 wherein the wafer support structure comprises at least one wafer slot sized to receive a silicon wafer therein.

3. (Original) The wafer boat of Claim 1 wherein the post coating surface finish of the wafer contact surface substantially prevents slip in silicon wafers of 300mm diameter or greater.

4. (Original) The wafer boat of Claim 1 wherein the post coating surface finish of the wafer contact surface substantially prevents slip in silicon wafers during thermal operations reaching temperatures of 720 degrees centigrade or greater.

5. (Original) The wafer boat of Claim 1 wherein the ceramic body comprises one of quartz, silicon carbide (SiC) and recrystallized SiC.

6. (Original) The wafer boat of Claim 1 wherein the ceramic coating comprises a SiC.

7. (Cancelled)

8. (Cancelled)

9. (Previously Amended) The wafer boat of Claim 1 wherein the ceramic coating has an impurity level of substantially 1 ppm or less.

10. (Cancelled)

11. (Original) The wafer boat of Claim 1 wherein the wafer boat is a vertical wafer boat.

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12. (Original) The wafer boat of Claim 2 comprising:  
a generally horizontal base;  
a support rod extending generally vertically from the base and having at least a pair of arms extending generally parallel relative to the base, the pair of arms defining the at least one wafer slot.

13. (Original) The wafer boat of Claim 12 wherein the support rod comprises a plurality of arms defining a plurality of slots each sized to receive a silicon wafer, each slot having the ceramic coating disposed thereon to define a plurality of wafer contact surfaces, each wafer contact surface having the post coating surface finish.

14. (Original) The wafer boat of Claim 12 wherein the support rod comprises a plurality of support rods.

15. (Original) The wafer boat of Claim 12 comprising a top plate attached to the upper distal end of the support rod.

16. (Original) The wafer boat of Claim 12 wherein the base comprises a stress relief slot and a location notch.

17. (Withdrawn)

18. (Withdrawn)

19. (Withdrawn)

20. (Withdrawn)

21. (Withdrawn)

22. (Withdrawn)

23. (Withdrawn)

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25. (Withdrawn)

26. (Withdrawn)

27. (Withdrawn)

28. (Withdrawn)

29. (Previously Amended) The wafer boat of Claim 1 comprising:  
a base;

a plurality of support rods extending generally upwards from the base, each support rod including at least one arm extending generally inwardly relative to the base, each arm having the post coating surface finish disposed thereon.

30. (Currently Amended) A wafer boat for supporting silicon wafers while substantially eliminating friction slip in said silicon wafers, the wafer boat comprising:

a ceramic body having at least one wafer support structure sized to support a silicon wafer thereon;

a ceramic coating disposed on a surface of the wafer support structure, the ceramic coating having an impurity migration preventing thickness that is substantially between 30 to 40 microns and a wafer contact surface, the wafer contact surface having a post coating surface finish;

wherein [the wafer contact surface is less than or substantially equal to 1/2 of the surface area of the wafer, and] the post coating surface finish [substantially prevents frictional slip in the silicon wafer] is less than or substantially equal to 0.4 micron.

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31. (Cancelled)

32. (Previously Added) The wafer boat of Claim 30 comprising:

a base;

a plurality of support rods extending generally upwards from the base, each support rod including at least one arm extending generally inwardly relative to the base, each arm having the post coating surface finish disposed thereon.